Description of the Invention

Planar Helix Slow-Wave Structure with Straight-Edge Connections

FIELD OF THE INVENTION

The present invention relates to the field of slow-wave structures and in particular discloses a new planar helix slow-wave structure and its input-output connections capable of broadband operation.

BACKGROUND OF THE INVENTION

A slow-wave structure, with phase velocity substantially slower than the speed of light, typically finds application in Traveling-Wave Tube (TWT). The TWT is an amplifier of microwave signals and it provides the largest bandwidth among all high power vacuum electronic devices. Two primary components of a TWT are an electron beam (e-beam) and a travelling electromagnetic (EM) wave. The EM wave is guided by a slow-wave structure. The slow-wave structure slows down the EM wave, ensuring 'velocity synchronism' between the electrons in the e-beam and the EM wave.

The most common slow-wave structure is the circular helix because of its un-matched capability for strong electron-wave interaction over large bandwidths. However, the circular helix is not a planar structure and it is not amenable to fabrication using printed-circuit or micro-fabrication techniques. Printed-circuit techniques are important for miniaturization as well as low-cost mass-production. Miniaturized TWTs can have widespread applications in communications, radar, spectroscopy etc. Moreover, since device dimensions scale inversely with frequency, at high frequencies the fabrication of the electron gun and slow-wave structure using conventional manufacturing technology becomes very difficult. Therefore micro-fabrication techniques are almost mandatory at high frequencies of operation. Further, an advantage of a planar slow-wave structure is the possibility of use of sheet geometry for electron beam. As compared to the round beam geometry, sheet beam geometry offers advantages of higher beam current capacity, decreased beam voltage and increased bandwidth.

SUMMARY OF THE PRESENT INVENTION

The primary object of the present invention is to disclose a broadband planar helix slow-wave structure and its broadband input-output connections.

The present invention consists of arrays of thin, parallel, conductors printed on top and bottom faces of a low-loss dielectric material or a substrate. The conductors in

the top and bottom arrays are inclined at different but symmetric pitch angles. The conjunction ends of the conductors in the top and bottom arrays are connected by vertical conductors. Planar helix structure is formed by the conductors in the arrays and the vertical conductors at the conjunction end. The vertical – or straight-edge connections - are simple and can be realized using printed-circuit or micro-fabrication techniques.

The slowing down effect in the present structure can be controlled by varying the pitch angle of the conductors in the top and bottom arrays, as well as by selecting the dielectric constant of the low-loss dielectric material.

The top face of the low-loss dielectric material can incorporate a pair of ground planes at some distance from the planar helix structure for dispersion shaping purpose. In a similar manner, the bottom face of the low-loss dielectric material can incorporate a pair of ground planes at some distance from the planar helix structure. Alternatively or additionally, the structure can incorporate a pair of ground planes at some height above and below the planar helix structure.

A vacuum tunnel with a rectangular cross-section smaller than the planar helix can be located centrally. Such a vacuum tunnel can accommodate a sheet electron beam for application in TWTs. The material surrounding the vacuum tunnel can form a vacuum envelope for the e-beam. Alternatively, the sheet beam can also be located just above (or just below), i.e., in close proximity with, the top or bottom arrays of conductors.

The present slow-wave structure can be integrated with input-output connections (also called feed), e.g., a broadband coplanar waveguide (CPW) feed. Broadband matching is achieved by tapering the CPW sections at the input and output of the helical structure. The input-output CPW sections can be straight or can include a right angle bend for different applications.

One possible method of fabricating the present slow-wave structure is to use multiple layers of low-loss dielectric materials. The arrays of conductors on the top and bottom faces can be fabricated on two separate printed-circuit boards using milling or photolithographic process. The two printed-circuit boards with arrays of conductors on the top and bottom faces can sandwich two or more un-metalized layers of low-loss dielectric material to form a rectangular tunnel within the planar helix structure. The vertical conductors on the conjunction ends of the conductors in the top and bottom arrays can be realized, for example, using vias or plated-through hole technology. The layers of low-loss dielectric materials may have the same dielectric constant or may have different dielectric constants.

A planar helical structure, as disclosed in U.S. Pat. Appl. No. 09/750,796, using through holes for electric connections at the conjunction end of microstrip sections,

appears similar to the structure proposed by us. However, that structure does not have input-output CPW sections, ground planes, or a vacuum tunnel. Moreover, the application proposed in U.S. Pat. Appl. No. 09/750,796 is as an antenna.

The usefulness of the present invention will be clear after reading the detailed description of the preferred embodiment with reference to the attached drawings.

BRIEF DESCRIPTION OF THE DRAWINGS

Notwithstanding any other forms which may fall within the scope of the present invention, preferred forms of the invention will now be described with reference to the accompanying drawings in which:

FIG. 1 is a perspective view of the present invention showing the planar helix with straight-edge connections in the presence of a dielectric substrate, vacuum tunnel and coplanar ground planes.

FIG. 2 is an enlarged view of **FIG. 1** showing the planar helix in the presence of a vacuum tunnel only.

FIG. 3 is a cross-section view of **FIG. 1**.

FIG. 4 is a top view of the planar helix with straight-edge connections, in the presence of a vacuum tunnel and coplanar ground planes, integrated with coplanar waveguide feed for both input and output. The coplanar waveguide feed also incorporates a right angle bend at both ends.

FIG. 5A shows the simulated phase velocity of the preferred embodiment, with and without coplanar ground planes.

FIG. 5B shows the simulated on-axis interaction impedance of the preferred embodiment, with and without coplanar ground planes.

FIG. 6 shows the simulated and measured *S*-parameters of the preferred embodiment of **FIG. 4**.

FIG. 7 shows the cross-section view of the fabricated embodiment of the planar helix with straight-edge connections.

FIG. 8 shows the simulated traveling wave amplification of the preferred embodiment of **FIG. 4** at 5GHz.

DESCRIPTION OF THE PREFERRED AND OTHER EMBODIMENTS

The preferred embodiment of the planar helix slow-wave structure with straight-edge connections, as shown in **FIG. 1**, consists of arrays of thin, parallel, conductors **101** and **102** printed on top and bottom faces, respectively, of a low-loss dielectric material **103**. The conjunction ends of the conductors **101** and **102** are connected by vertical conductors **104**. Circular rings **105,** with diameter greater than the diameter of vertical conductors **104,** help to ensure connections between **101, 102** and **104**. The planar helix structure is formed by of the combination of multiple conductors **101**, **102**, **104** and **105**. A vacuum tunnel **106,** with a rectangular cross section smaller than that of the planar helix**,** is located centrally within the planar helix. For TWT applications, this vacuum tunnel can accommodate a sheet electron beam. Two coplanar ground planes **107a** and **107b** are located on the top face of the low-loss dielectric material **103** with a small separation from the edges of the circular rings **105**.

As indicated in an enlarged view of the planar helix structure in **FIG. 2**, the conductors **101** on the top face are oriented at an angle Ψ_1 with respect to the *y*-direction and the conductors **102** on the bottom face are oriented at an angle $-\Psi_1$ with respect to the *y*-direction. *L* is the period of the planar helix; *SW* is the width of conductors **101** and **102** and *VD* is the diameter of the vertical conductors **104**. **FIG. 3** shows the rectangular cross-section of the structure in the *xy*-plane. The cross-section dimensions of the planar helix and the vacuum tunnel are (2*a*, 2*b*) and (2c, 2d), respectively. The period *L* is related to the cross section dimensions and pitch angle as

$$L = 4b\tan\left(\Psi_1\right) \tag{1}$$

The separation between the ground planes **107a** and **107b** on the top face and the edges of the circular rings **105** is *s*. The vacuum in the tunnel has a dielectric constant $\varepsilon_{r1} = 1$. The dielectric material **103** surrounding the vacuum tunnel has a dielectric constant ε_{r2}. A ceramic type of dielectric material is preferable for the high temperature and vacuum environment in a TWT; the ceramic material can also act as a vacuum envelope.

FIG. 4 shows the top-view of the planar helix with straight-edge connections, in the presence of coplanar ground planes, integrated with coplanar waveguide (CPW) ports **401a** and **401b** with a characteristic impedance of 50Ω. Tapered CPW sections, **402a** and **402b,** are incorporated between the 50Ω CPW ports and the input and output, **403a** and **403b,** of the planar helix. Wideband impedance matching can be achieved by optimizing the length of the CPW tapered sections **402a** and **402b** and the impedance at the end of the tapered sections, **404a** and **404b,** respectively. In order to provide CPW ports on the same side of the structure and to accommodate the electron gun and collector in TWT applications, the CPW portions incorporate a right angle bend, **405a** and **405b**. Air bridges **406a**, **406b**, **406c** and **406d**, **406e** and **406f** are added at the CPW right angle bends as well as at the input and output of the planar

helix, to ensure that the ground planes **107a** and **107b** are at the same potential.

One period of the embodiment of the planar helix in the presence of vacuum tunnel has been simulated, with and without coplanar ground planes, using CST Microwave Studio Eigenmode Solver. The embodiment dimensions are a = 0.75mm, b = 3mm, c = 0.25mm, d = 2mm, $\Psi_1 = 10^0$, SW = 0.7mm, VD = 0.36mm, $\varepsilon_{r1} = 1$, ε_{r2} = 3.02 and circular ring diameter of 0.71mm. For the embodiment with coplanar ground planes, s is taken as 0.5mm. **FIG. 5A** shows a comparison of the normalized phase velocity (v_p/c) between the embodiment with (**501**) and without (**502**) coplanar ground planes. The curve **501** shows that a reduced phase velocity variation can be obtained by putting coplanar ground planes on the top face of the low-loss dielectric material. The variation of the phase velocity can be further reduced by reducing s or by introducing similar coplanar ground planes at the bottom face also. The phase velocity and operating bandwidth of the embodiment is affected by the dimensions of the planar helix structure, size of the vacuum tunnel, as well as the material of the low-loss dielectric material. **FIG. 5B** shows the simulated on-axis interaction impedance of the embodiment with (**503**) and without (**504**) coplanar ground planes. Although the variation of phase velocity can be reduced by the coplanar ground planes, these also reduce the on-axis interaction impedance, especially at lower frequencies, as shown in **503**. A lower on-axis interaction impedance may result in a lower gain in the TWT applications.

The embodiment with coplanar ground planes on the top face of the low-loss dielectric material, integrated with CPW feed as shown in **FIG. 4**, has been designed using CST Microwave Studio. Printed-circuit board Rogers RO3203, with thickness 1.5mm and dielectric constant 3.02, was selected for this design. The simulated S parameters, taking into account the loss in the dielectric and conducting materials, are shown in **FIG. 6**. In this configuration -10 dB S_{11} bandwidth, shown in the curve **601**, covers the frequency range from 1 GHz to around 9.5 GHz – which is almost a decade of bandwidth (1 : 9.5). The S_{21}, **602**, drops significantly at high frequencies. This is mainly due to low conductivity of the vertical conductors **104** on the conjunction ends of the conductors **101** and **102**.

As shown in **FIG. 7**, an embodiment of the planar helix can be fabricated using 4 pieces of low-loss dielectric material **701**, **702**, **703a** and **703b**. The conductors **101** and **102** on the top and bottom faces are fabricated on two separate printed-circuit boards, **701** and **702**, using milling or photolithographic process. **701** and **702** sandwich two un-metalized pieces of the low-loss dielectric material, **703a** and **703b**, to form a rectangular tunnel within the planar helix structure. The vertical conductors, **104**, on the conjunction ends of the conductors in the top and bottom array can be realized, for example, using vias or plated-through hole technology. The pieces **701**, **702**, **703a** and **703b** can be secured together by using screw and nut sets **704**. The low-loss dielectric material, **701**, **702**, **703a** and **703b**, may have the same dielectric constant, as shown in **FIG. 3**, or may have different dielectric constants.

Following the configuration in **FIG. 7**, the embodiment shown in **FIG. 4** has been fabricated, using Rogers RO3203 dielectric substrate with a thickness of 0.5 mm for **701**, **702**, **703a** and **703b**. Three layers of 0.5mm thick dielectric substrate are stacked together to produce an overall 1.5 mm high (a = 0.75mm) planar helix structure. The pieces **703a** and **703b** are separated by 4mm (d = 2mm). **FIG. 6** includes the measured *S* parameters **603** and **604** of the fabricated structure. The measured results, **603** and **604**, generally match well the simulated ones, **601** and **602**.

The small signal simulation of the electron beam and EM wave interaction for the embodiment shown in **FIG. 4** has been performed using CST Particle Studio Particle-In-Cell solver. A sheet electron beams with a cross-section half that of the vacuum tunnel **106** is used in the simulations. Following the curve **501** in **FIG. 5A**, the normalized phase velocity of the EM wave is 0.126 at 5 GHz. Therefore, the beam voltage is set to 4070 V, corresponding to a beam normalized velocity of 0.127, which is slightly higher than that for the EM wave. 5 mA of beam current and 100 periods of the planar helix are assumed. **FIG. 8** shows the simulated input and output RF signals, **801** and **802**, respectively, as a function of time. A 5 GHz sinusoidal RF signal, **801**, with input power of 0.5 mW is injected into the input CPW port. The amplification of the input signal can be seen clearly in **802**. From **801**, the input wave amplitude is 0.02236 (square root of 0.5mW), and from **802**, the output wave amplitude is 0.32 after 9 ns. Therefore, the small signal gain is 23.1 dB.

Only a few implementations are disclosed here. However, it would be appreciated by a person skilled in the art that numerous variations and/or modifications may be made to the present invention as shown in the specific embodiments without departing from the spirit or scope of the invention as broadly described. The present embodiments are, therefore, to be considered in all respects to be illustrative and not restrictive.

Some relevant References

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CLAIMS

What is claimed is what is described and illustrated, including:

1. A planar helix slow-wave structure with straight-edge connections:
   The planar helix structure consists of two arrays of thin, parallel, conductors printed on top and bottom faces of a low-loss dielectric material or substrate;
   the conductors in the arrays printed on the top and bottom faces are inclined at different but symmetric pitch angles;
   the conjunction ends of the conductors on the top and bottom faces are connected by vertical conductors;
   circular rings with a diameter greater than the diameter of the vertical conductors to ensure proper connections between vertical conductors and the conductors on the top and bottom faces;
   a vacuum tunnel inside the planar helix structure.
2. The structure as claimed in claim **1**, wherein each of the two arrays of conductors can be printed on a different layer of low-loss dielectric material.
3. The structure as claimed in claim **2**, wherein there can be more layers of low-loss dielectric material between the two layers of low-loss dielectric material on which each of the two arrays is printed.
4. The structure as claimed in claim **2**, wherein there can be more layers of low-loss dielectric material outside the two layers of low-loss dielectric material on which each of the two arrays is printed.
5. The structure as claimed in claims **1-4**, further comprising optional coplanar ground planes on the top face of the low-loss dielectric material with some lateral separation from the edges of the circular rings.
6. The structure as claimed in claims **1-4**, further comprising optional coplanar ground planes on the bottom face of the low-loss dielectric material with some separation from the edges of the circular rings.
7. The structure as claimed in claims **1-4**, further comprising, as an alternative or in addition to claims **5-6**, a pair of ground planes at some height above and below the planar helix.
8. The structure as claimed in claims **1-4**, wherein the size of the vacuum tunnel can be varied.
9. The structure as claimed in claims **1-4**, wherein the pitch angle of the conductors on the top and bottom faces can be changed.
10. The structure as claimed in claims **1-4**, wherein the length of the conductors on the top and bottom faces as well as the height of the vertical conductors can be changed.
11. The structure as claimed in claims **1-4**, wherein the dielectric constant of the layers of low-loss dielectric materials can be changed.
12. The structure as claimed in claims **5-6**, wherein the separation of the ground planes from the edges of the circular rings can be changed.
13. The structure as claimed in claim **7**, wherein the height of the ground planes above and below the planar helix can be changed.

14. The structure as claimed in claims **1-7**, further comprising a coplanar waveguide feed. The coplanar waveguide feed consists of:
    coplanar waveguide ports of arbitrary impedance for input/output of a high frequency signal;
    coplanar waveguide sections of arbitrary impedance at the input/output ends of the planar helix;
    tapered coplanar waveguide sections joining the coplanar waveguide ports and the coplanar waveguide sections at the input/output ends of the planar helix;
    optional coplanar waveguide right angle bends near the input/output ends of the planar helix;
    air bridges at the coplanar waveguide right angle bends and at the input/output ends of the planar helix**;**
15. The feed as claimed in claim **14**, wherein the length of the tapered sections can be changed.
16. The feed as claimed in claim **14**, wherein the coplanar waveguide can have bends, for instance, to accommodate the location of an electron gun and a collector for TWT applications.
17. A fabrication method for the structure claimed in claims **1-7:**
    The top and bottom arrays of conductors are fabricated on two separate pieces of a low-loss dielectric material using milling or photolithographic process and sandwich two or more spaced-apart middle pieces of a low-loss dielectric material;
    the two or more middle pieces of the low-loss dielectric material are un-metallised;
    the vertical conductors on the conjunction ends of the conductors in the top and bottom arrays can be realized using vias or plated-through hole technology;
    the multiple layers of the low-loss dielectric materials are stacked and secured together.
18. The method as claimed in claim **17**, wherein the multiple pieces of the low-loss dielectric material may have same or different dielectric constants.
19. The method as claimed in claim **17**, wherein the height of the vacuum tunnel is determined by the thickness of the middle pieces of the low-loss dielectric material.
20. The method as claimed in claim **17**, wherein the width of the vacuum tunnel is determined by the lateral spacing between the middle pieces of the low-loss dielectric material.
21. The method as claimed in claim **17**, wherein the height of the planar helix structure is determined by the thickness of the multiple layers of the low-loss dielectric materials between the two outermost surfaces of the structure.